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(19) (11) Publication number: **60220729 A**

PATENT ABSTRACTS OF JAPAN

(21) Application number: **59078144** (51) Int. Cl.: **B29C 51/10**

(22) Application date: **18.04.84**

(30) Priority:		(71) Applicant: HITACHI CHEM CO LTD
(43) Date of application publication:	05.11.85	(72) Inventor: KAKIGI TADASHI TEJIMA TERUO
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(54) FORMING METHOD OF SKIN MATERIAL

(57) Abstract:

PURPOSE: To transfer uneven embossed pattern to a sheet in good reproducibility by vacuum-forming a skin sheet with a female mold according to normal process and then heating it in the state of vacuum attraction.

CONSTITUTION: When uneven embossed pattern and complicated uneven shape of skin material are transferred onto the surface of an automobile instrument panel pad etc. the skin sheet is vacuum-formed with a

female mold having engraved embossed pattern on the mold surface, according to the normal process, then, the sheet is heated on the back of the skin at a temperature near the melting point in the state of vacuum attraction.

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